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Electronic Patent Application Submission
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EFS ID: 53498
Application ID: 10680783
Title of Invention: HIGH-PRESSURE PROCESSING
CHAMBER FOR A
SEMICONDUCTOR WAFER
First Named Inventor: William Jones
Domestic/Foreign Application: Domestic Application
Filing Date: 2003-10-06
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Statement
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Trademark Office,ou=Department of Commerce,o=U.S. Government,c=US
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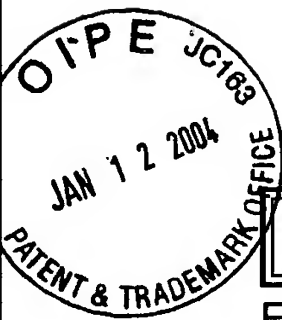


TRANSMITTAL

Electronic Version v1.1


Stylesheet Version v1.1.0

Title of Invention	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER									
Application Number: 10/680783 										
Date: 2003-10-06										
First Named Applicant: William Dale Jones										
Confirmation Number: 5859										
Attorney Docket Number:										
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<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Thomas B. Haverstock Registered Number: 32571</td><td>/tbh/</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>SSI04001C-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	SSI04001C-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
us-ids	SSI04001C-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER						
Application Number:		10/680783					
Confirmation Number:		5859					
First Named Applicant:		William Jones					
Attorney Docket Number:							
Search string:		(5882165 or 5888050 or 5898727 or 5900107 or 5904737 or 5928389 or 5932100 or 5934856 or 5934991 or 5979306 or 5980648 or 5981399 or 5989342 or 6005226 or 6017820 or 6029371 or 6035871 or 6037277 or 6053348 or 6056008 or 6067728 or 6077053 or 6077321 or 6082150 or 6085935 or 6097015 or 6128830 or 6145519 or 6159295 or 6164297 or 6186722 or 6203582 or 6216364 or 6228563 or 6235634 or 6239038 or 6241825 or 6251250 or 6244121 or 6277753 or 6286231 or 6305677 or 6334266 or 6344174 or 6388317 or 6389677 or 6418956 or 6436824 or 6454945 or 6464790).pn.					
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
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Remarks

Note: Remarks are not for responding to an office action.

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Signature

Examiner Name	Date